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Docket No.: 2328-050

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Jian J. CHEN

U.S. Patent Application No. 09/821,027

Filed: March 30, 2001

For: INDUCTIVE PLASMA PROCESSOR HAVING COIL WITH PLURAL WINDINGS
AND METHOD OF CONTROLLING PLASMA DENSITY

: : EXPEDITED PROCEDURE
: : Response under 37 CFR 1.116
: Confirmation No.
5541
:
: Group Art Unit: 1763
:
: Examiner: CROWELL, ANNA M.

AMENDMENT UNDER RULE 116

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

This paper is submitted in reply to the Office Action mailed December 23, 2003, which was made Final. Applicants respectfully request that the following amendments **as to form** be entered to place this application in condition for allowance.